THE LUVOIR ULTRAVIOLET MULTI-OBJECT SPECTROGRAPH (LUMOS): A' AND B

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F2F 7, 10 May 2018

LUMOS A -> A': What's new

- Reconfigured MOS channel, tried different internal configurations, returned to something similar to –A because of time constraints. Would like to push to rectangular FOV again to maximize MOS targets/field, add LSB mode
- Peak effective Areas increased ~20 -30%, # of shutters on sky decreased (~1200 -> 840 because of smaller FOV allocation). Spec Res is higher, ang res is ~slightly lower (but above spec)
- FUV imager is ~done and HRS is mostly TBD, HRS design is straightforward (Garrett?)
- Per request, picked up some of ONIRS capability, R ~ 35K MOS from 400 – 1000 nm (red response is poor)









Focal Plane Array

 $3x7 array \rightarrow 7x10 array$

Mech.

MOS FUV Focal Plane Array

> High-res (R ≥ 100K) point source spectrograph (complements CNES / POLLUX instrument; at 20-40x higher sensitivity in unpolarized mode, > 100x higher sensitivity vs. polarized mode)

LUMOS A: Eff. Area

LUMOS A': Eff. Area



TO DO: LSB mode $\lambda \sim 150 \text{ nm}$ $<R> = 55K, <\theta> = 19 \text{mas}$ LUMOS A: ResolutionLUMOS A': Resolution









 $\lambda \sim 120 \ nm$

 $< R > = 44K, < \theta > = 18mas$



LUMOS-A' Performance

		Res Pow	
Mada	Devel (vere)	(50% Of	Ang Res (50% of
wode	Band (nm)	FUV)	FOV, masj
G120M	100-140	44K	18
G150M	130-170	55K	19
G180M	160-200	56K	15
G155L	100-200	13K	24
G145LL	100-200	TBD	TBD
G300M	200-400	39K	7
G700M	400-1000	39K	10
FUV Img	100 - 200	N/A	13





$\lambda \sim 300 \text{ nm}$ <R> = 39K, < θ > = 7.5mas LUMOS A': Resolution



0

60

30

) 0 Arcseconds

-60

-60

-30

$\lambda \sim 600 \text{ nm}$ <R> = 39K, < θ > = 10mas LUMOS A': Resolution





LUMOS-A' and –B: TO DOs



- G145LL, LSB mode for G155L (R ~ 10K, "big" pixel/sr to reduce background)
- 2 HRS mode
- 3 BEF analysis (NUV detectors)

- Received telescope package ~3 days ago, redesign of MOS underway
- (2) HRS and FUV imaging modes ?
- ③ Mass, mass, and mass



LUMOS B: Mass challenges. Max total instrument mass: 200 – 250 kg

LUMOS-AIndiss Col% of totalLUMOS-BIndiss Col% of total270K LUMOS Truss Enclosure (LTE)267.36014.8%270K LUMOS Truss Enclosure0.0000.0%0280K LUMOS A1 Optical Bench Enclosure186.19010.3%280K LUMOS A1 Optical Bench37.2388.8%0.2280K Optical Bench Assembly379.52021.0%280K Optical Bench Assembly75.90417.9%0.2Calibration System Assembly (mounted to Optical Bench)15.1040.8%Calibration System Assembly15.1043.6%1Multi-Object Spectrograph Channel Assembly237.57713.2%Multi-Object Spectrograph Channel Assembly142.54633.6%0.6FUV High Resolution Spectrometer Channel Assembly28.5211.6%FUV High Resolution Spectrometer Channel Assembly0.0000.0%0FUV High Resolution Subsystem196.57410.8%Electrical Subassembly0.0000.0%0Harness116.6776.5%Harness23.3155.5%0.2Thermal Subsystem7.5000.4%Contamination Subsystem7.5001.8%1Total1718.24395.2%Total404.08795.2%5%100.0%5% Miscellaneous Hardware85.9124.8%5%6%404.08795.2%5%5% Miscellaneous Hardware85.912100.0%5%6%404.08795.2%100.0%		Mass CBE			Mass CBE		
270K LUMOS Truss Enclosure (LTE) 267.360 14.8% 270K LUMOS Truss Enclosure 0.000 0.0% 0 Assembly 186.190 10.3% 280K LUMOS A1 Optical Bench Enclosure (OBE) Assembly 37.238 8.8% 0.2 280K Optical Bench Assembly 379.520 21.0% 280K Optical Bench Assembly 75.904 17.9% 0.2 Calibration System Assembly (mounted to Optical Bench) 15.104 0.8% Calibration System Assembly 16.104 3.6% 1 Multi-Object Spectrograph Channel Assembly 237.577 13.2% Multi-Object Spectrograph Channel Assembly 142.546 33.6% 0.6 FUV Imager Channel Assembly 29.521 1.6% FUV Imager Channel Assembly 0.000 0.0% 0 Electrical Subassembly 48.500 2.7% Electrical Subassembly 0.000 0.0% 0 Harness 116.577 6.5% Harness 23.315 5.5% 0.2 Contamination Subsystem 195.574 10.8% Thermal Subsystem 78.230 18.4% 0.4 Contamination Subs	LUMOS-A	(kg)	% of total	LUMOS-B	(kg)	% of total	Scale Factor
2280K LUMOS A1 Optical Bench Enclosure (OBE) Assembly 186.190 10.3% 280K LUMOS A1 Optical Bench Enclosure (OBE) Assembly 37.238 8.8% 0.2 280K Optical Bench Assembly 379.520 21.0% 280K Optical Bench Assembly 75.904 17.9% 0.2 Calibration System Assembly (mounted to Optical Bench) 15.104 0.8% Calibration System Assembly (mounted to Optical Bench) 15.104 3.6% 1 Multi-Object Spectrograph Channel Assembly 237.577 13.2% Calibration System Assembly (mounted to Optical Bench) 0.000 0.0% 0 FUV Imager Channel Assembly 234.821 13.0% FUV Imager Channel Assembly 0.000 0.0% 0 FUV High Resolution Spectrometer Channel Assembly 29.521 1.6% Spectrometer Channel Assembly 0.000 0.0% 0 Electrical Subassembly 48.500 2.7% Electrical Subassembly 24.250 6.7% 0.5 Harness 116.577 6.5% Harness 23.315 5.5% 0.2 Thermal Subsystem 7.500 0.4% Contamination Subsystem 7.500<	270K LUMOS Truss Enclosure (LTE) Assembly	267.360	14.8%	270K LUMOS Truss Enclosure (LTE) Assembly	0.000	0.0%	0
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May 14, 2018

LUMOS: The LUVOIR Ultraviolet Multi-Object Spectrograph

LUMOS Performance.



Prototypical Observation:

 $F_{\lambda} \approx 1 \times 10^{-15} \text{ erg cm}^{-2} \text{ s}^{-1} \text{ Å}^{-1}$ to S/N = 25/resel in 5 hours

HST Comparison:

1) HST-COS @ R = 17,000 T_{exp} = 76 ks

2) HST-STIS @ R = 114,000 T_{exp} = 150 Ms (~5 yr) High-res ($R \ge 100K$) point source spectrograph



	• FUV Imager
ilter	Bandpass
110M	102 – 118 nm
140M	130 – 150 nm
160M	150 – 170 nm
G180M	170 – 190 nm
150W	135 – 175 nm
Dpen	100 – 200 nm
'GALEX FUV"	~ 135 – 200 nm

Detector-limited 12.6 mas imaging over the entire FOV. Multi-layer filters have ~ 85% peak reflection in band, ~ 1% out of band (Rodreguez-De Marcos et al. 2016)

LUMOS Performance Summary: see France et al. 2017

power, bandpass, and angular resolution boxes, the *target value is on top*, the *average value at the center of the field* delivered by the LUMOS design is beneath in bold and parentheses, and the *average parameter value over 80% of the imaging field-of-view is beneath in bold, italics, and parentheses*. The lower number demonstrates that LUMOS achieves the spectral and spatial resolution goals across the majority of its spectral and spatial detector area.

Instrument Parameter	G120M	G150M	G180M	G155L	G145LL	G300M	FUV Imaging
Spectral Resolving	30,000	30,000	30,000	8,000	500	30,000	Avg, cen of FOV
Power	(42,000) <i>(30,300)</i>	(54,500) <i>(37,750)</i>	(63,200) (40,750)	(16,000) <i>(11,550)</i>	(500)	(40,600) <i>×</i> (28,000) <i>×</i>	Avg, 80% of FOV
Optimized Spectral Bandpass (Total)	100 – 140nm (92.5 – 147.4 nm)	130 – 170nm (123.4 – 176.6 nm)	160 – 200nm (153.4 – 206.6 nm)	100 – 200nm (92.0 – 208.2 nm)	100 – 200nm	200 – 400nm	100 – 200nm
Angular Resolution	50 mas (11 mas) <i>(17 mas)</i>	50 mas (15 mas) (19.5 mas)	50 mas (17 mas) <i>(24 mas)</i>	50 mas (15 mas) (27.5 mas)	100 mas (32 mas)	50 mas (8 mas) (26 mas)	25 mas (12.6 mas) (12.6 mas)
Temporal Resolution	1 msec	1 msec	1 msec	1 msec	1 msec	1 sec	1 msec
Peak Throughput	5% 7.5%	5% 7.5%	5% 7.5%	5% 7.5%	5% 7.5%	5% 12%	10% 11%
Field of View	2' × 2' (3' × 1.6')	2' × 2' (3' × 1.6')	2' × 2' (3' × 1.6')	2' × 2' (3' × 1.6')	2' × 2' (3' × 1.6')	2' × 2' (1.3' × 1.6')	2' × 2' (2' × 2')

LUMOS MOS Example Science Program: Surveying the Birthplace of Planets





LUMOS MOS Example Science Surveying the Birthplace



Map 5 regions in Orion from 1 – 10 Myr, 10s – 100s protoplanetary disks in each Every target field would return more data than all previous HST UV observations of disks

1700



May 14, 2018

LUMOS: The LUVOIR Ultraviolet Multi-Object Spectrograph

FIN



LUMOS Performance**

- *R* ≥ *HST*-COS everywhere in FOV
 - Extended source R ~ 1/6 point source R for filled slit
 - ~ 1200 shutters available per exposure in M & L modes
 - (~ 10,000 for G145LL)

	rocolution		
		Res Pow	
		(50% of	Ang Res (50% of
Mode	Band (nm)	FOV)	FOV, mas)
G120M	100-140	44K	18
G150M	130-170	55K	19
G180M	160-200	56K	15
G155L	100-200	13K	24
G145LL	100-200	TBD	





LUMOS technology gaps

- Broadband mirror coatings for $\lambda > 100$ nm
 - Partial success already work is moving in the right direction (also ALD)
 environmental tests and scalability
- Large format photon counting detectors (FUV and NUV)
 - Cross-strip borosilicate MCPs
 - $\circ~$ sCMOS or CCDs
- Low scatter (holographic) aberration correcting gratings
- Microshutter Arrays for spectral multiplexing
- High groove efficiency, low scatter echelle gratings

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Broadband advanced coatings, large format detectors, and spacequalified MSAs all being developed and flight tested as part of NASAsupported Sounding Rocket missions, APRA programs, and Roman Technology Fellowships (Pis – France, Green, McCandliss, Siegmund, Vallerga, Nikzad, Quijada, Fleming, and others)

LUMOS: Specs and Performance

	Microshutter Array Assembly (MSAA)	FUV MOS and Imager MCP	NUV MOS CMOS
FOV	1.6' x 3.0'	1.6' x 3.0'	1.6' x 1.3'
Element Size/ Resolution	100 x 200 um (pitch)	20 um (resel)	6.5 um (pixel)
Elements per Tile	840 x 420 shutters	10Kx10K resels	8192 x 8192
Tiles per Array	3 x 2	2 x 2 (Imager 1)	7 x 3
Detector Tile Dimension s	88.2mm x 85.7mm	200mm x 200mm	54mm x 55mm
Detector Package Dimension s	444mm x 316mm x 150mm	600mm x 600mm 140mm	400mm x 200mm x 140mm



- eLiF Reflectivity: Fleming et al. 2016
- MSAA: JWST NIRSpec (Heritage)

LUMOS: Specs and Performance



Particle Background Reduction

The particle background at L2 is 3 – 5 times that in LEO. (!) Measured by LRO-LAMP, interplanetary coast on ALICE spectrographs

This will dominate the Background Equivalent Flux (BEF) for the open-face MCPs and limit faint object spectroscopy, especially for extended objects.

We are adopting two strategies to mitigate the background:

ALD/Borosilicate glass plates, reduce sensitivity to MeV gammarays by $\sim 2 - 3$ ($\sim 5 - 10$ times lower dark rates in lab total)

(Anti-) Coincident detection/rejection

Particle Background Reduction

Very low MCP background (~0.03 cm⁻² sec⁻¹) is achievable with ALD MCPs. But having intrinsically low MCP background is not enough. It is often the case that the local high energy particle & gamma rates dominate.



Illustration of the anti-coincidence shield flown on the EURD instrument in 1997. 85% rejection of muon events in ground tests, MCP background rate \sim 0.06 cm⁻² sec⁻¹ (Bowyer et al 1997).

The timing resolution with photon counting MCP detectors is at the 100ps level. High energy particle events look like single events and can be discriminated with high efficiency by amplitude rejection and by timing coincidence. A combination of radiation shielding, amplitude thresholding, coincidence timing rejection and intrinsically low background / gamma sensitivity could make background improvements of an order of magnitude.

Slide from Ossy Siegmund – UC Berkele

LUMOS High-Resolution Channel: E135H





LUMOS High-Resolution Channel







LUMOS High-Resolution Performance

Prototypical Observation:

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HST Comparison:

1) HST-COS @ R = 17,000 T_{exp} = 76 ks

2) HST-STIS @ R = 114,000 T_{exp} = 150 Ms (~5 yr)



LUMOS FUV Imager



LUMOS Target Acquisition and BOP



LUMOS (Design team – Colorado, Engineering team – GSFC)

One of the three primary instruments voted on by the STDT at the second face-to-face meeting at Goddard in Aug 2016 (w/ HDI, coronagraph)

- First design for Architecture A (15m) complete
- Instrument Design Lab run (GSFC), May 15-19 2017
- LUMOS team has its own technology gap list, collaboration on development programs

"LUMOS-B" for 9m Architecture B beginning



LUMOS Structure and Mechanical

LUMOS Truss Enclosure (LTE); mounted with flexures to Optical Bench; composed of two halves; square tubes (carbon composite)

170 K Radiator; mounted to LTE; alum. HC and facesheets

Graduate research assistant storage area





LUVOIR Overview Large UV / Optical / Infrared Surveyor (LUVOIR) A space telescope concept in tradition of Hubble Far-UV to Near-IR bandpass ~ 9 – 15 m aperture diameter Suite of imagers and spectrographs → broad program of exoplanet science and general astrophysics Serviceable and upgradable, largely GO observatory "Space Observatory for the 21st Century" **Decades of science** Ability to answer questions we have not yet conceived

LUMOS: Specs and Performance



THE LUVOIR ULTRAVIOLET MULTI-OBJECT SPECTROGRAPH (LUMOS): INSTRUMENT OVERVIEW AND PERFORMANCE

Kevin France (PI - Colorado), Brian Fleming (IS & deputy-Pl Colorado), Garrett West (GSFC), Stephan McCandliss (JHU), Matthew R. Bolcar (GSFC), Walter Harris (Arizona), Leonidas Moustakas (JPL), John O'Meara (St. Michael's), Ilaria Pascucci (Arizona), Jane Rigby (GSFC), David Schiminovich (Columbia), Jason Tumlinson (STScI)



LUVOIR astrophysics science drivers

Characterizing the gas phase of the cosmos:

- IGM, CGM H I, CIII, C IV, O VI, Ne VIII
- ISM, Galaxies Si II, Mg II, C II, C I, H, D, H₂, HD
- PPDs C IV, H₂, CO, H₂O, CO₂, OH, CH₄
- Exoplanet atmospheric and exospheric markers H I, O I, C II, Mg II, O₂, O₃, H₂

All of these are well-traced (often best-traced) in the UV (100 – 400nm) CGM, galaxies, disks are often extended objects. (imaging, multi-object spec) QSO tomography and disks require high velocity resolution (med/high-res) Lyman Continuum and other low-brightness sources require large statistics (high throughput, multi-object spec)

LUMOS requires multi-object, wide-field imaging spectroscopy capability with both high and low resolution modes, with sensitivity into the Lyman UV (at least to 100 nm).

